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U.S. PATENT DOCUMENTS

Ex. Int.		Document Number							Date	Name		Class	Sub-class	Filing Date If Approp.
100	AA	5	1	4	4	3	6	3	9/1/92	Wittekoek et al		355	53	1/24/91
100	AB	4	5	4	0	2	7	7	9/10/85	Mayer et al		355	53	6/24/83
100	AC	4	7	3	7	8	2	3	4/12/88	Bouwer et al		355	53	10/14/86
100	AD	5	0	2	6	1	6	6	6/25/91	Van der Werf		356	401	10/1/84
100	AE	5	1	9	1	2	0	0	3/2/93	Van der Werf		250	201	12/16/91
100	AF	4	3	5	6	3	9	2	10/26/82	Wittekoek et al		250	201	6/11/80
100	AG	4	8	6	1	1	6	2	8/29/89	Ina et al		356	401	11/15/88
100	AH	5	4	1	4	5	1	4	5/9/95	Smith et al		356	363	6/1/93
100	AI	4	7	7	8	2	7	5	10/18/88	Van den Brink		356	401	9/24/86
100	AJ	4	2	5	1	1	6	0	2/17/81	Bouwhuis et al		356	401	7/13/78
100	AK	5	2	4	3	1	9	5	9/7/93	Nishi		250	548	12/29/92

FOREIGN PATENT DOCUMENTS

		Document Number							Date	Country	Class	Sub-Class	Trans.		
													Yes	No	
100	AL	0	4	9	8	4	9	9	A	1	8/12/92	Europe			X
100	AM	9	8	3	9	6	8	9	A	1	9/11/98	World			X

OTHER (Including Author, Title, Date, Pertinent Pages, Etc.)

100	AN	"Submicrometer Lithographic Alignment and Overlay Strategies", by Saleem H. Zaidi et al, SPIE Vol. 1343, 1990, pages 245-255.
100	AO	"Submicron 1:1 Optical Lighography", by David A. Markle, Semiconductor International May 1986.
Examiner	<i>Surendra</i>	Date Considered 8/17/94